

# ALICE 3 Inner Tracker

Riunione Referee ALICE – 20-21 Luglio 2023

Giacomo Contin - Università di Trieste & INFN Sezione di Trieste

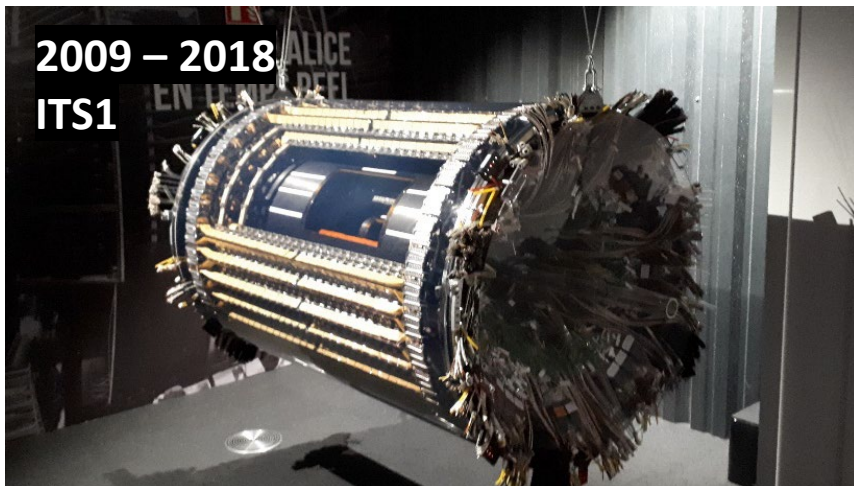
# Outline

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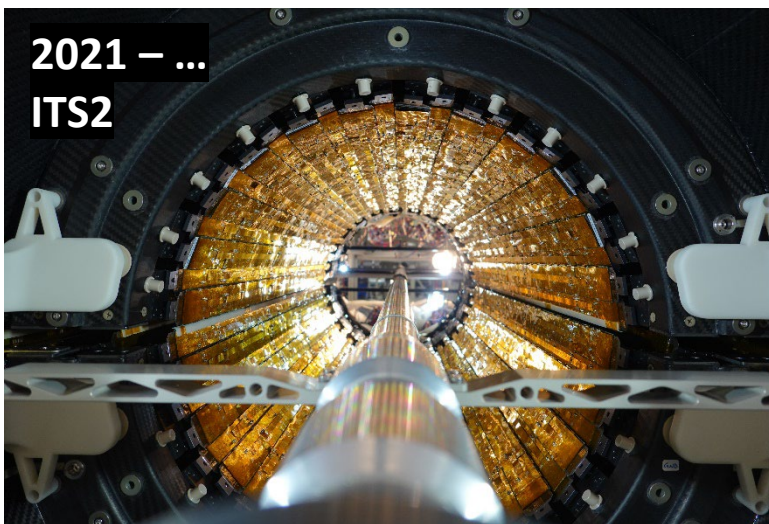
- ITS3 as a first step towards ALICE 3 Inner Tracker
- Planned R&D activities for ALICE 3 Inner Tracker
- Requests for 2024

# Silicon tracker evolution in ALICE



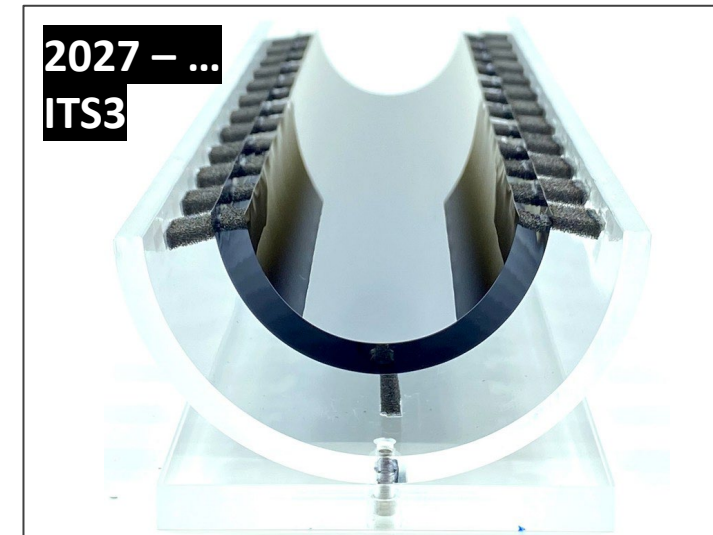
2009 – 2018  
ITS1

- **ITS1:** three silicon technologies
  - Hybrid pixels
  - Drift chambers
  - Micro-strips
- Operated for 10 years in ALICE
  - Essential ingredient for its physics output (secondary vertex reconstruction)



2021 – ...  
ITS2

- **ITS2:** a large-scale MAPS detector
  - Monolithic Active Pixel Sensors
  - 10 m<sup>2</sup> active area
- Currently taking data

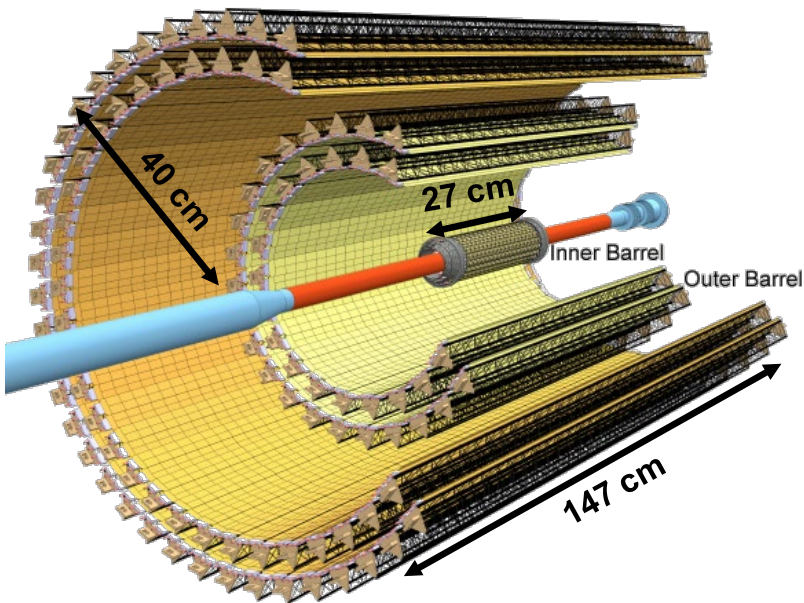


2027 – ...  
ITS3

- **ITS3:** wafer-scale, bent silicon
  - Replacing the ITS2 innermost layers
  - Novel detector technology
- R&D endorsed by LHCC and running at full speed
- TDR in preparation

**INFN Leadership in all  
Projects from the start**

# ITS2: from R&D to detector implementation



## ITS2 specifications

### 7 layers:

all MAPS  
10 m<sup>2</sup>, 24k chips, 12.5×10<sup>9</sup> Pixels

### Innermost layer:

radial distance: 23 mm  
material: X/X<sub>0</sub> = 0.35%  
pitch: 29 × 27 μm<sup>2</sup>

Rate capability: 100 kHz (Pb-Pb)

### ITS2 expected performance

pointing resolutions of 15 μm (in r and z) at p<sub>T</sub>=1GeV/c  
tracking efficiencies > 90% for particles with p<sub>T</sub>>200 MeV/c

- **ITS2**: the largest detector based on MAPS technology
  - Sensor (ALPIDE) and apparatus **fully developed within ALICE**
  - R&D program started ~12 years ago
  - Construction involved > 10 institutes
  - Currently taking data in ALICE

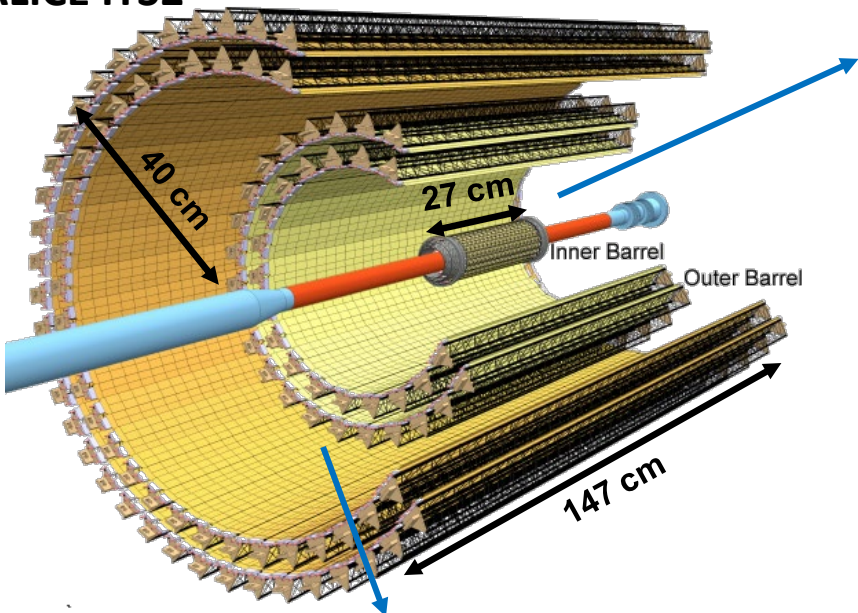
INFN BA, BR/PV, CA,  
CT, LNF, PD, TO, TS

- Safe resource investment for concrete high-quality results

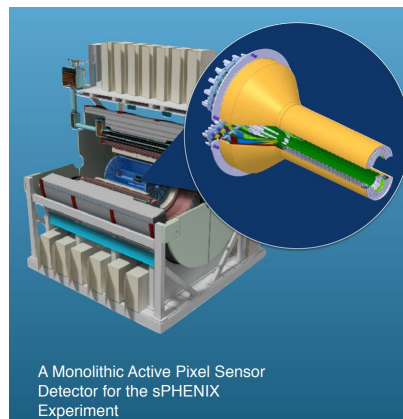


# ITS2 technology transfer to other projects

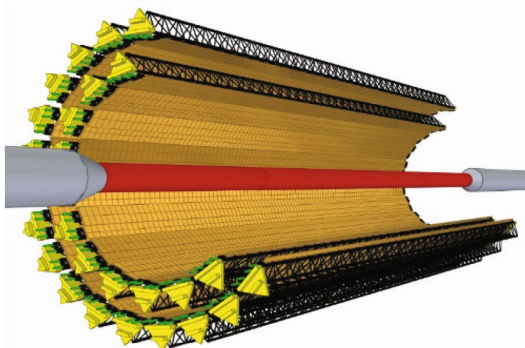
## ALICE ITS2



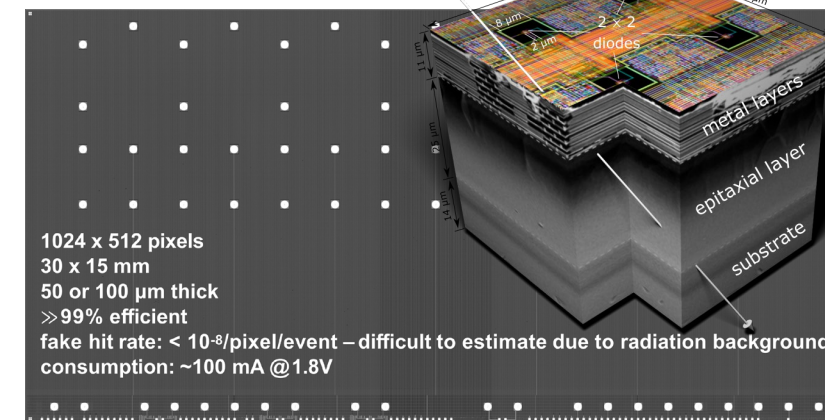
## SPHENIX MVTX @RHIC



## MPD Inner Tracker @NICA



## ITS2 ALPIDE sensor



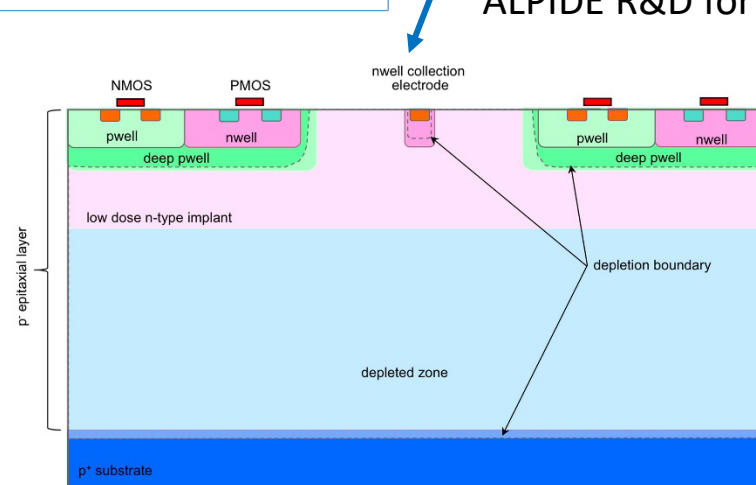
- **Modified process** developed and prototyped within ALPIDE R&D for better timing and radiation hardness

- Now adopted or considered by future experiments...

- **HADES, CBM, PANDA, NUSTAR, NA61, CSES2-Limadou, iMPACT, COMPASS++/AMBER, pCT, ePIC ...**

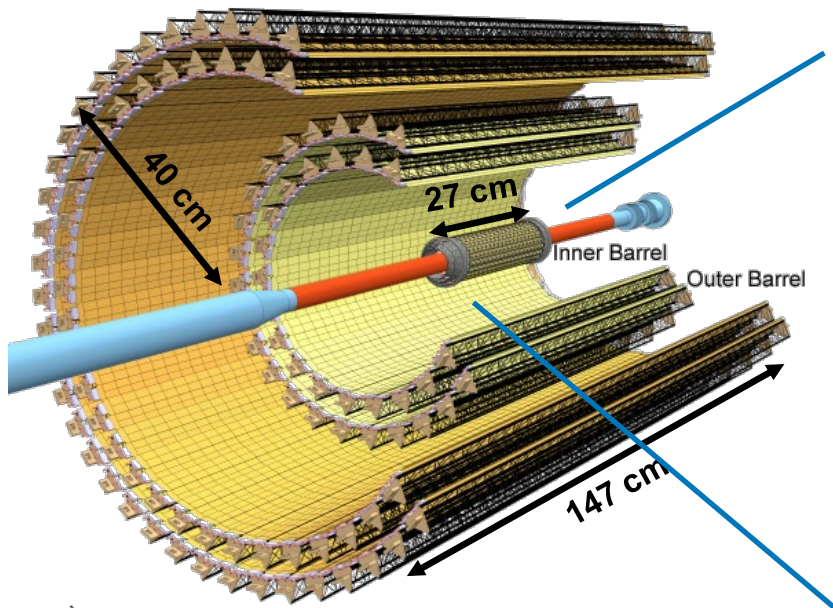
- & chip developments:

- **MALTA,**
- **CLICpix,**
- **FastPix, ...**

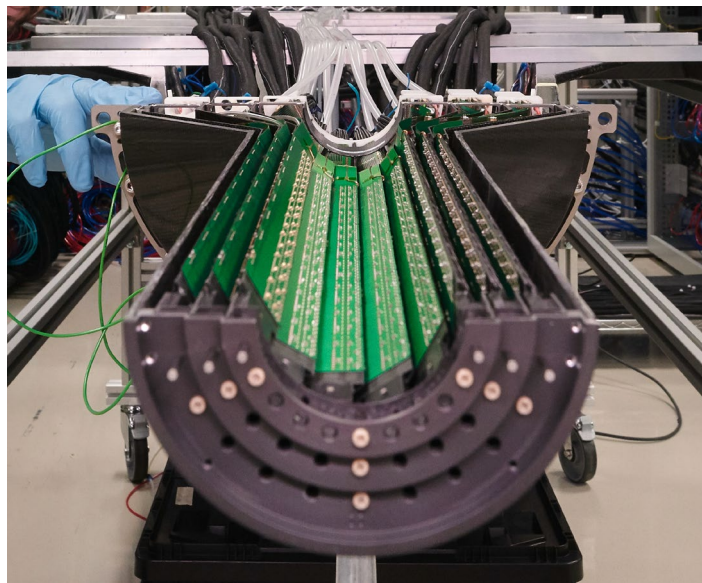


- **Detector replicas** for new experiments

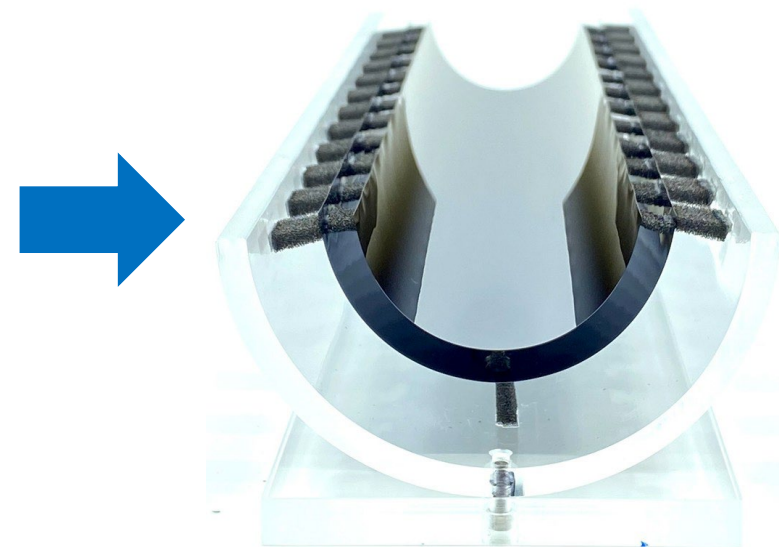
# ITS3: wafer-scale sensors with bent geometry



ITS2 Inner Barrel

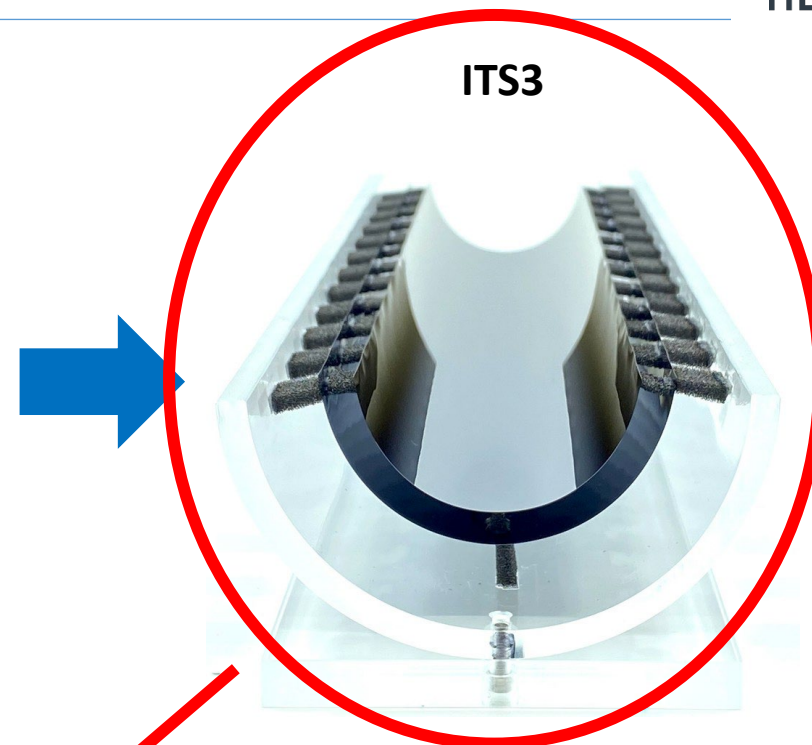
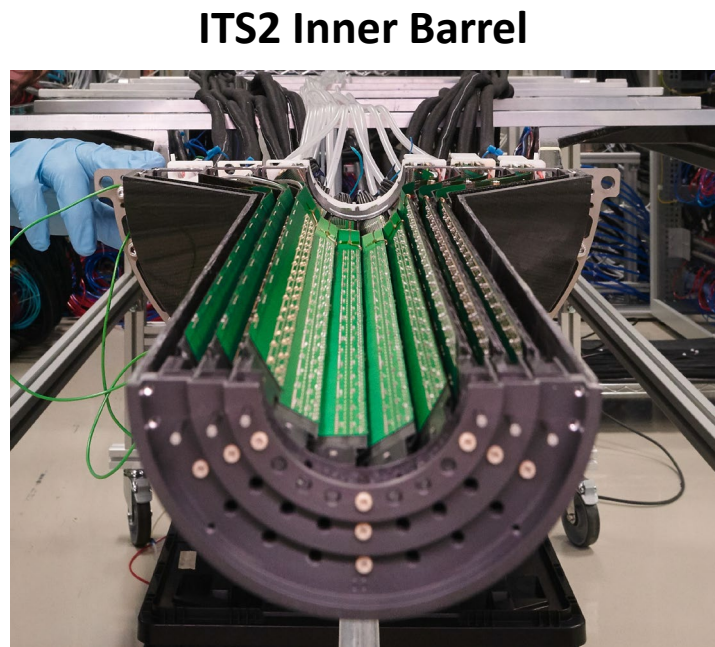
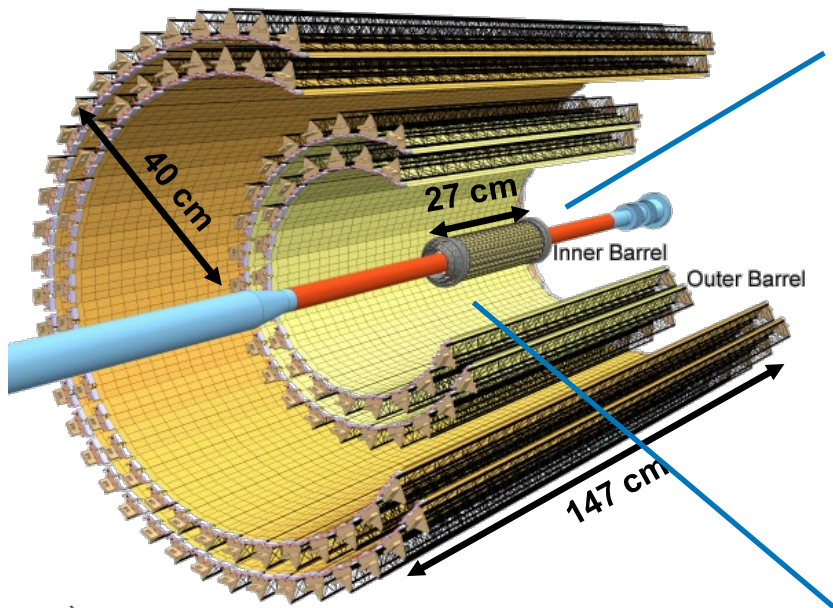


ITS3



- **Motivation:** further material budget reduction → improve tracking resolution x2 → large physics impact
- **Proposal:** replace detector staves (tiled by several chips) by wafer-scale sensors that are bent around the beam pipe

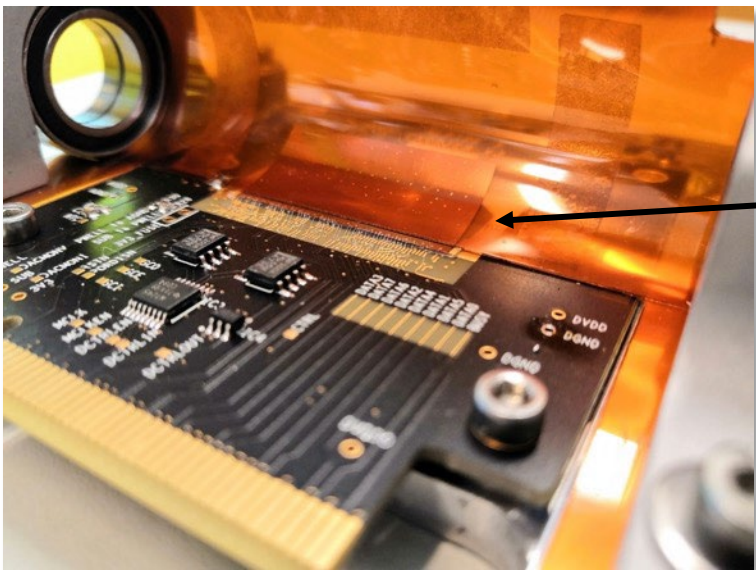
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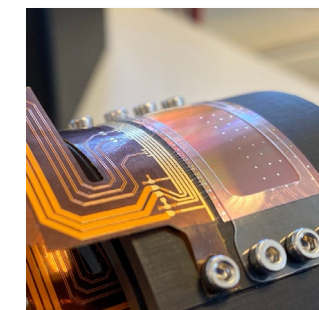
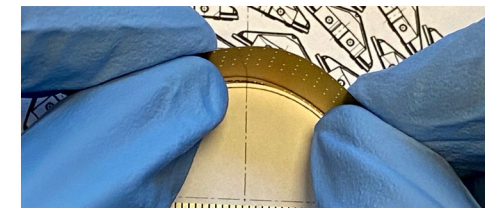
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**First step towards the ALICE 3 Inner Tracker sensor and detector concept**

# R&D towards ALICE 3: bent MAPS sensors

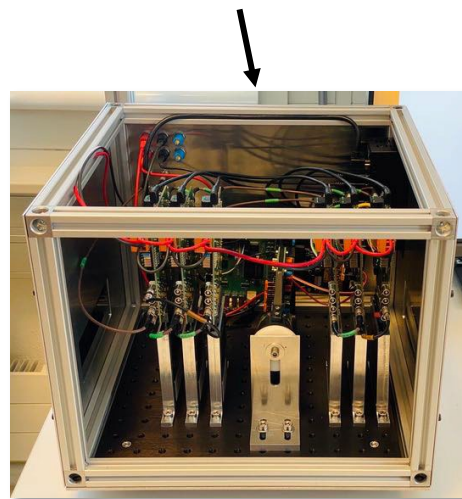


- Silicon becomes flexible below 50  $\mu\text{m}$  thickness
- **Idea:** bend existing MAPS sensors (ALPIDE) and interconnect to readout/control system
- Measure the bent sensor performance and compare with flat sensors

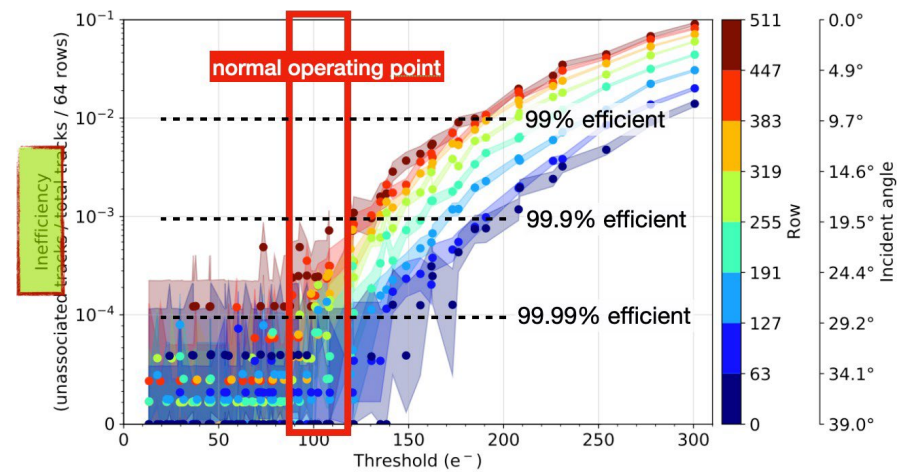


- R&D carried out within INFN**
- Bending mechanics and procedures
  - Curvature precision measurements
  - Wire-bonding on curved surface
  - Laboratory characterization
  - In-beam performance measurements

INFN BA, BO, CA, CT, PD, TO, TS



*Bent MAPS work!*



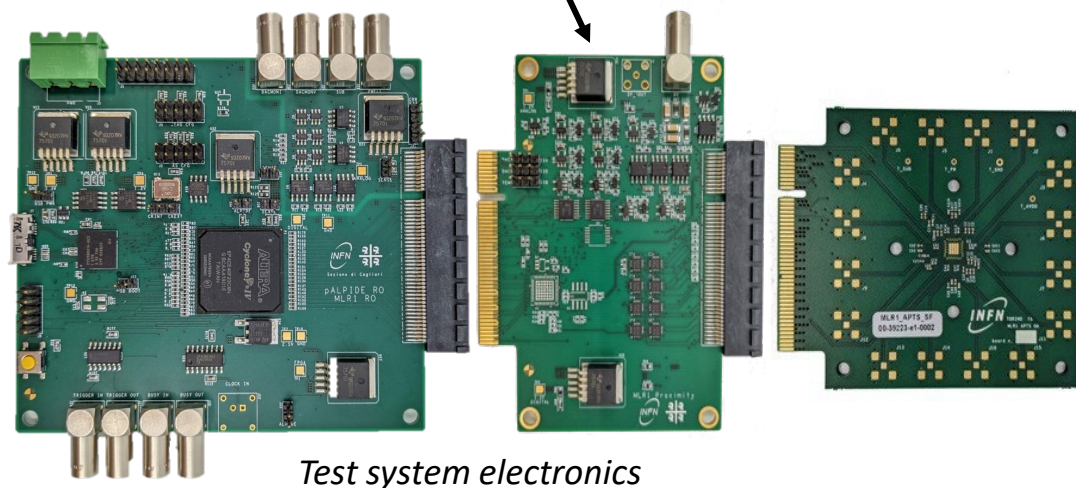
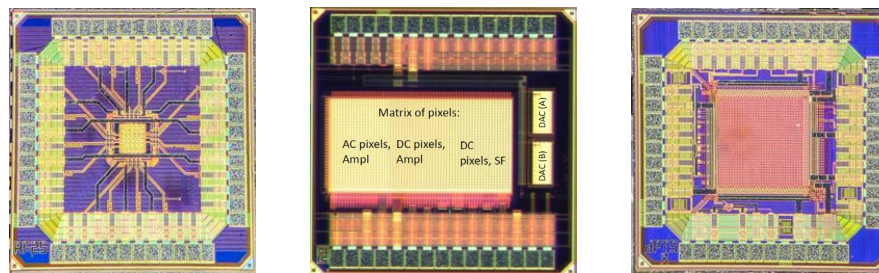
<https://doi.org/10.1016/j.nima.2021.166280>



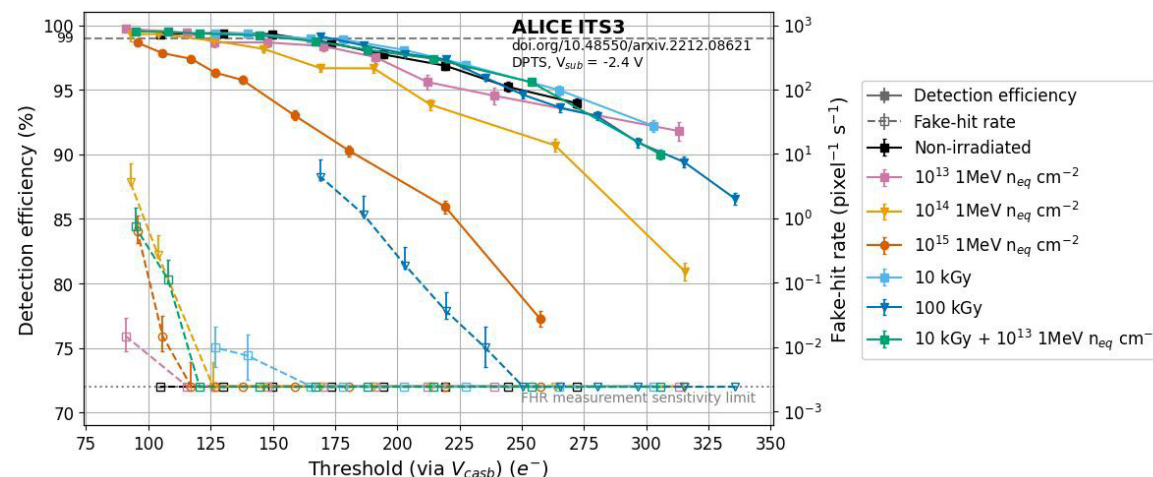
# R&D towards ALICE 3: 65 nm CMOS process

- **65 nm CMOS process** exploration
  - test structures design & characterization with lab measurements and beam tests
- test system design & production

APTS, CE65 and DPTS: 65 nm CMOS test structures



Digital pixel test structure efficient after irradiation

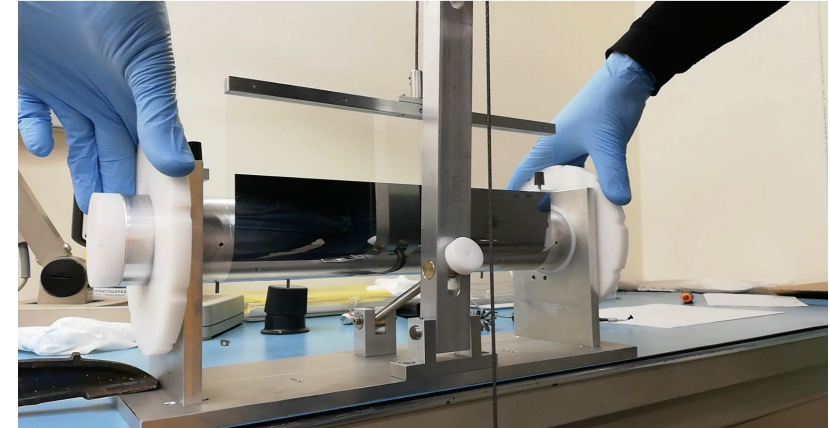
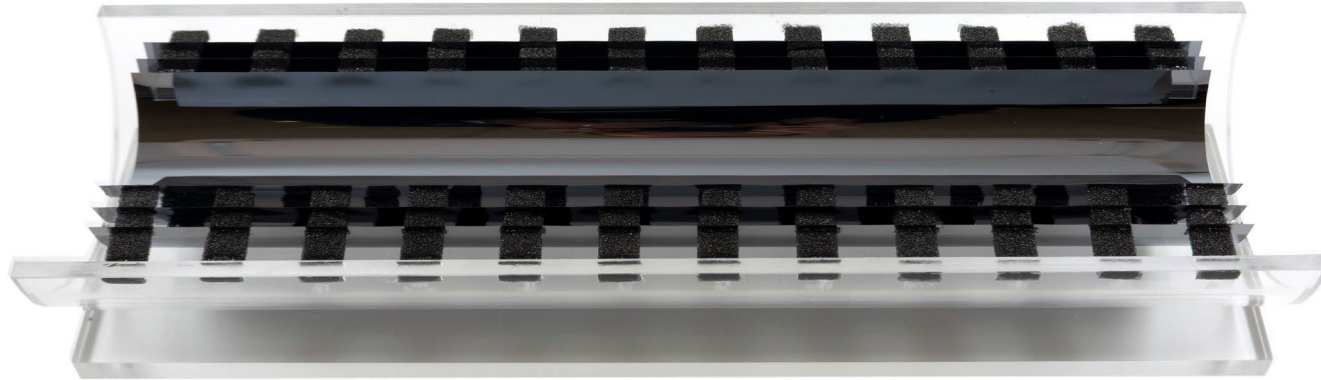


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Submitted to NIM A: <https://arxiv.org/abs/2212.08621>

# R&D towards ALICE 3: mechanics & interconnections

- Large-area bending and mechanical supports



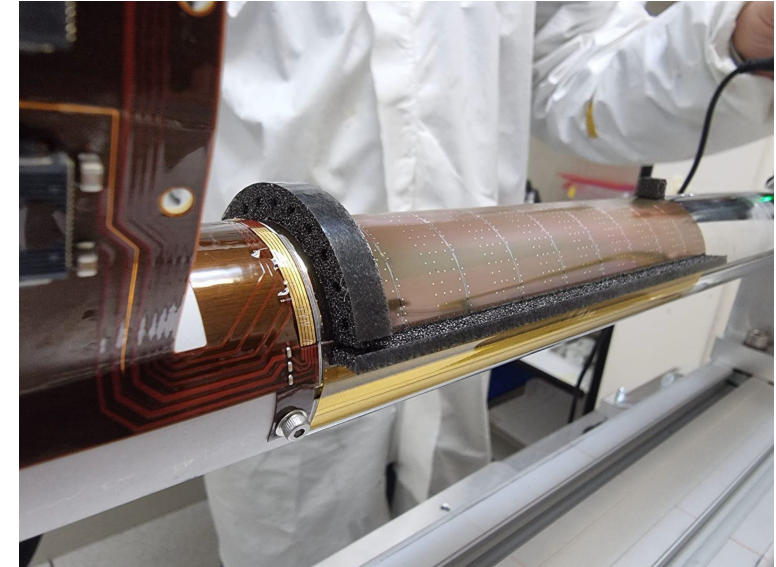
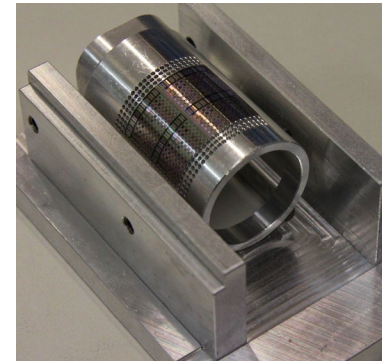
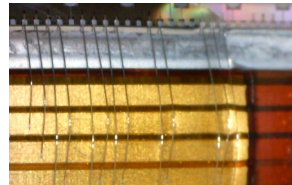
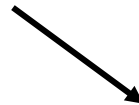
- Full-scale ITS3 Layer prototype in 180 nm CMOS



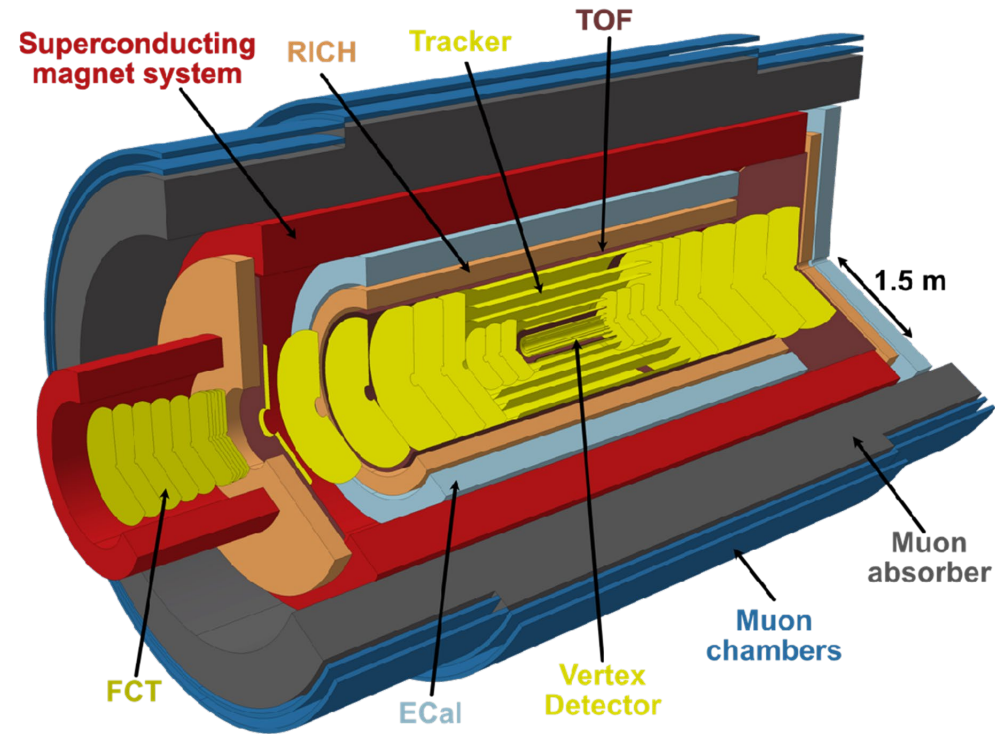
- Bent 65 nm CMOS structure characterization



- Interconnections on bent substrate



INFN BA, TO, TS

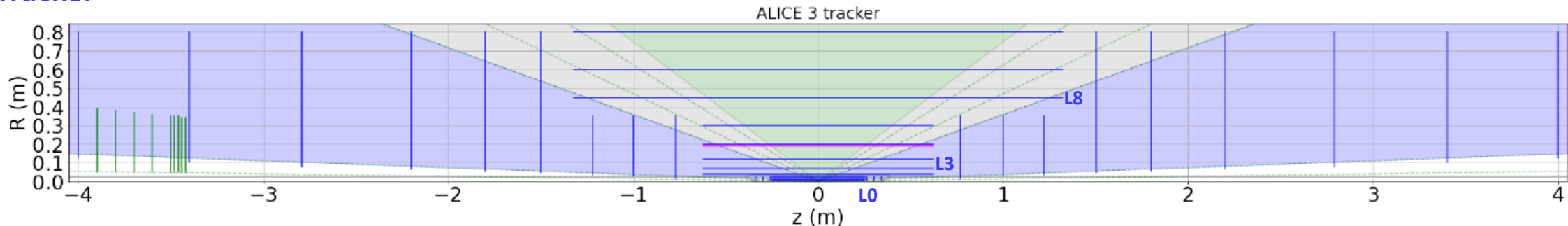


# R&D for ALICE 3 Inner Tracker

BA, BS/PV, CA, CT/ME, PD, LNF, TO, TS

# Tracker layout (LoI)

## Full Tracker



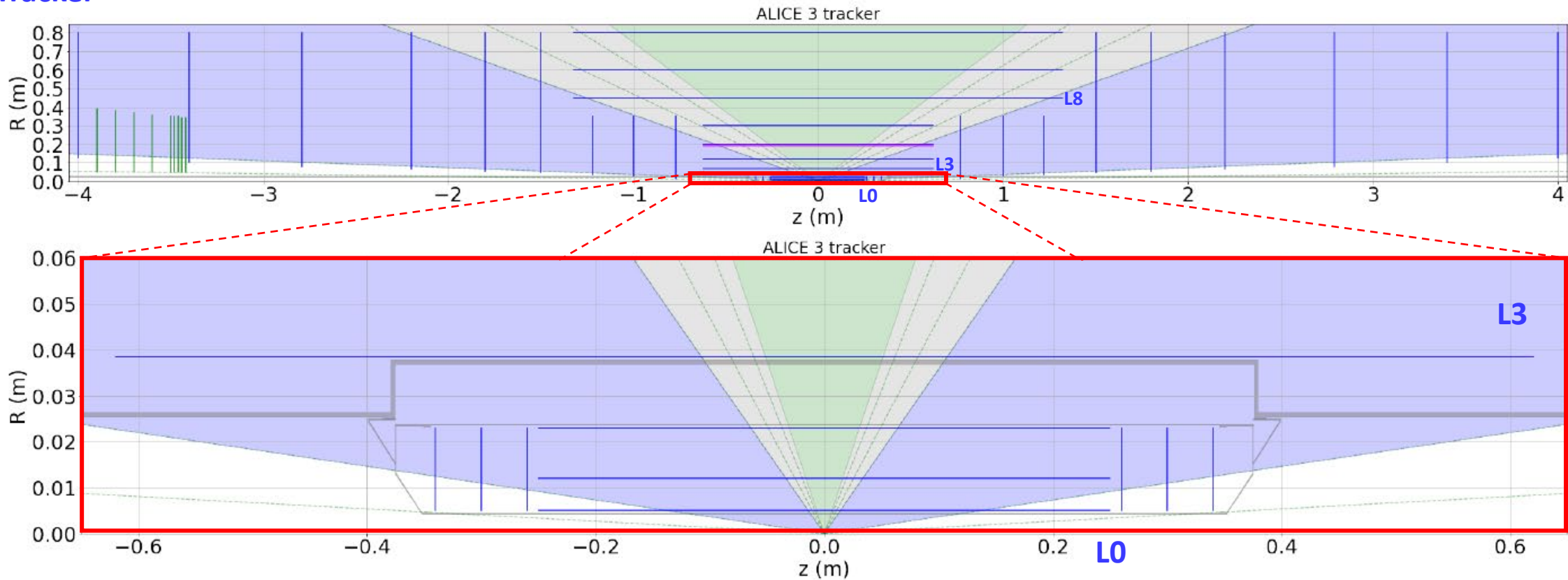
- **11 barrels + 12 discs per side**
- **Main distinction: inside/outside the beampipe**
  - material thickness: 0.1 / 1.0 % $X_0$
  - intrinsic resolution: 2.5 / 10  $\mu\text{m}$
- **Barrel lengths and radii, disk positions: not fully optimized yet**

Layer	Material thickness (% $X_0$ )	Intrinsic resolution ( $\mu\text{m}$ )	Barrel layers		Forward discs		
			Length (z) (cm)	Radius (r) (cm)	Position ( z ) (cm)	$R_{\text{in}}$ (cm)	$R_{\text{out}}$ (cm)
0	0.1	2.5	50	0.50	26	0.50	3
1	0.1	2.5	50	1.20	30	0.50	3
2	0.1	2.5	50	2.50	34	0.50	3
3	1	10	124	3.75	77	5	35
4	1	10	124	7	100	5	35
5	1	10	124	12	122	5	35
6	1	10	124	20	150	5	80
7	1	10	124	30	180	5	80
8	1	10	264	45	220	5	80
9	1	10	264	60	279	5	80
10	1	10	264	80	340	5	80
11	1				400	5	80

Inside the beam pipe

# Tracker layout (LoI)

## Full Tracker



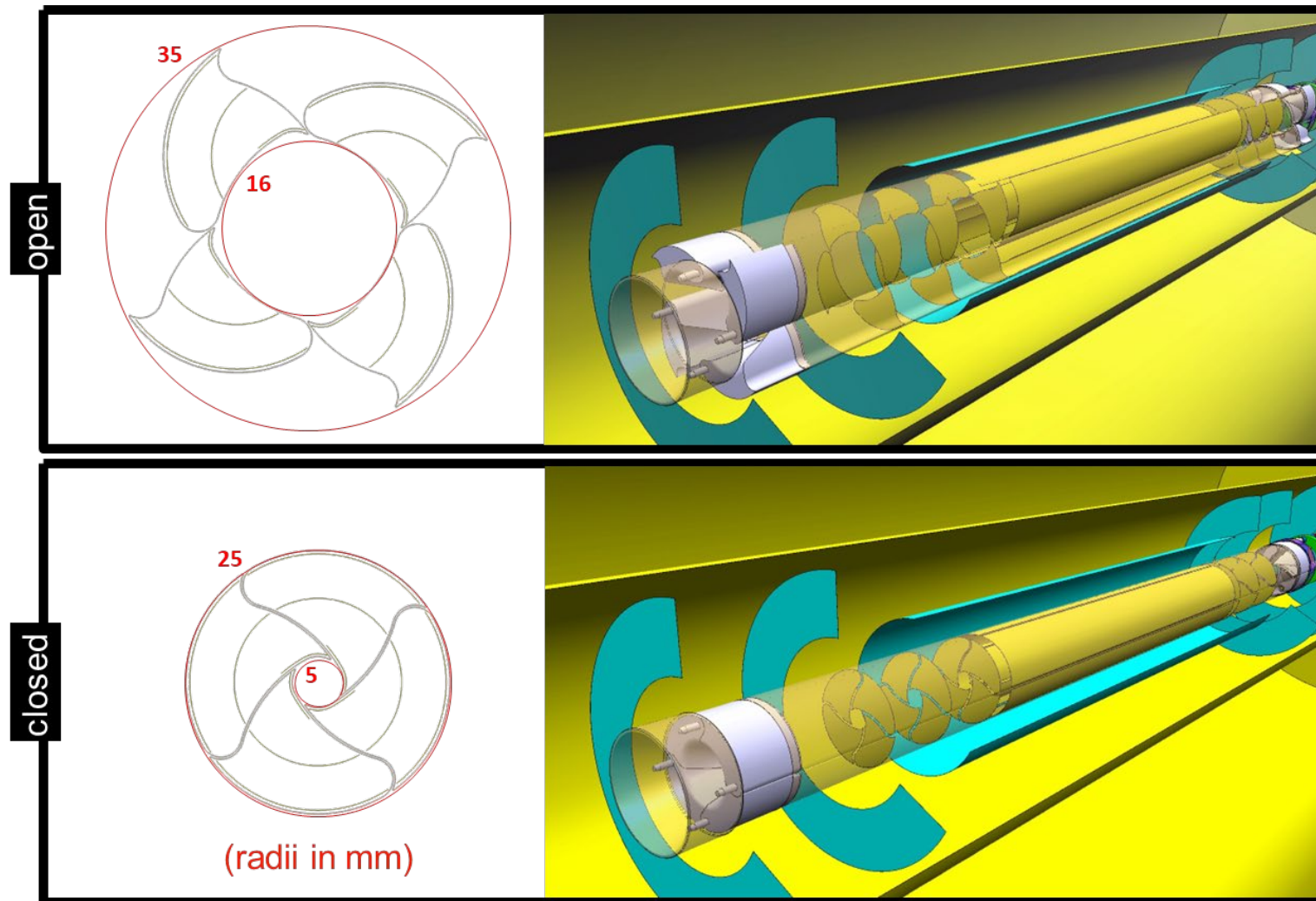
## Vertex Layers + L3

**Zoom in on the first 4 layers**

# ALICE 3 Tracker — Iris: inside the beam pipe

- **Curved sensors**
- **5 mm** from IP
  - Crucial to gain highest possible vertex resolution
  - Extremely challenging requirements on sensor
- **Retractable mechanics** inside the beam pipe
- **Vacuum-compatible** services and interconnections

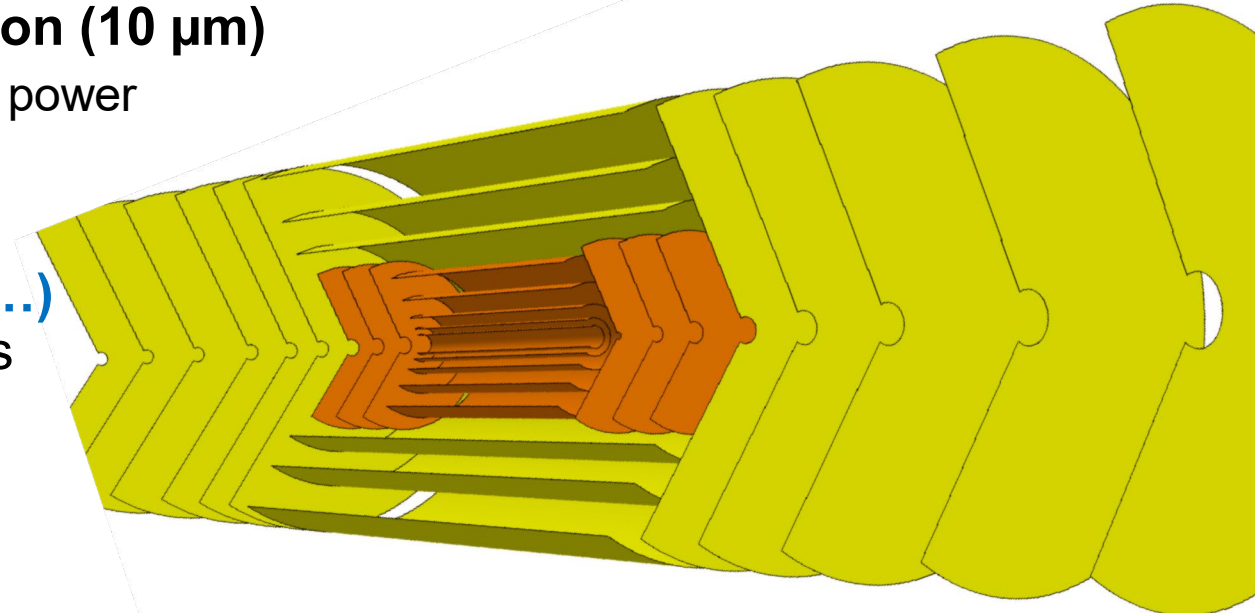
INFN R&D on  
**Vertex Detector (= Iris)**



# ALICE 3 Tracker — Outside the beam pipe

- **~60 m<sup>2</sup> active surface**
  - Heavily relies on a module concept that can be automated/industrialised
  - ITS2 module production for 10 m<sup>2</sup> kept 5 institutes busy for years
- **Low material budget (1% X<sub>0</sub>):**
  - Reducing power consumption will be key
  - Powering granularity and services (serial powering, DC/DC, on-detector switches)
- **Less stringent requirement on position resolution (10 μm)**
  - Will allow for larger pixels/grouping of pixels to reduce power
  - Reducing the noise contribution to the bandwidth
- **A specific design for the Middle Layers (L3-L4-...)**  
with lower material budget and different pixel specs will improve the p<sub>T</sub> resolution at very low p<sub>T</sub>

*Physics simulations to define optimal layout are ongoing*



**INFN R&D on Middle Layers**

# R&D INFN su Inner Tracker = Vertex + Middle Layers



- Sviluppo del **sensore ALICE 3 Inner Tracker**
  - Sensore ITS3 e' il primo passo dello sviluppo del sensore per ALICE 3 Inner Tracker
  - Per 2024 non c'e' richiesta dedicata per ALICE 3 chip
  - Possibile la caratterizzazione orientata ad ALICE 3
- **Indispensabile anticipare le attivita' orientate al *risk mitigation*** su chip per ALICE 3
  - Abilita' del sensore *stitched* ITS di distribuire la tensione di alimentazione su grandi distanze attraverso gli strati metallici interni al silicio e' ancora sotto esame
  - Strato di redistribuzione applicato con manifattura additiva
- Sviluppo **tecnologie compatibili col vuoto** per Iris
  - Meccaniche, sistema di raffreddamento, interconnessioni, materiali e colle
- Esplorazione comparata di **possibili layout dei Middle Layers**

		2023				2024				2025				
		Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	
		Run 3												
TPSCo 65m Engineering Runs						ER2 (ITS3)				ER3 (ITS3)				
Inner Tracker	Vertex Detector	Study of ITS3 prototypes wrt. use in ALICE3 VD												
		Chip												
		Petals					Design				Prototyping			
		Beam pipe					Design				Prototyping			
		Mechanics					Design				Prototyping			
	Cooling Plant									Design				
	Services									Design				
	Middle Layers	Study of ITS3 prototypes wrt. use in ALICE3 ML												
		Chip												
		Module					Design				Prototyping			
Mechanics						Design				Prototyping				
Services										Design				
Detector									Prot					

from preliminary ALICE 3 planning

**Inner Tracker WG**  
 CERN, Italy, Czech Rep,  
 Netherlands, Norway, Ukraine





# ALICE 3 Inner Tracker **Sensor** development

	Vertex Detector	Outer Tracker	ITS3	ITS2
Pixel size ( $\mu\text{m}^2$ )	$\div 9$ O(10 x 10)	$\times 2.8$ O(50 x 50)	O(20 x 20)	O(30 x 30)
Position resolution ( $\mu\text{m}$ )	$\div 2$ 2.5	$\times 2$ 10	5	5
Time resolution (ns RMS)	$\div 10$ 100	$\div 10$ 100	O(1000)	O(1000)
Shaping time (ns RMS)	$\div 25$ 200	$\div 25$ 200	O(5000)	O(5000)
Fake-hit rate (/ pixel / event)	$\approx$ $< 10^{-8}$	$\approx$ $< 10^{-8}$	$< 10^{-7}$	$\ll 10^{-6}$
Power consumption (mW / $\text{cm}^2$ )	+ 75% 70	67% 20	20 (pixel matrix)	40 / 30**
Particle hit density (MHz / $\text{cm}^2$ )	$\times 20$ 94	$\div 100$ 0.06	8.5	5
Non-Ionising Energy Loss (1 MeV $n_{\text{eq}}$ / $\text{cm}^2$ )	$\times 3000$ $1 \times 10^{16}$	$\times 100$ $2 \times 10^{14}$	$3 \times 10^{12}$	$3 \times 10^{12}$
Total Ionising Dose (Mrad)	$\times 1000$ 300	$\times 20$ 5	0.3	0.3

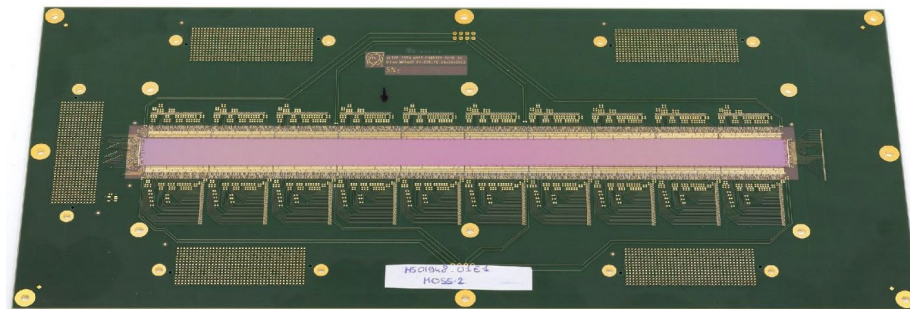
\*\* Innermost layers / outer layers

- Improving ITS2/ITS3 performance in all aspects
- Current goals extremely challenging, will be revised based on simulations, results from ITS3 development, and available resources
- **No requests for 2024: ITS3 sensor IS the prototype for ALICE 3**

*Different optimisations  
at different radii*

# ALICE 3 IT Sensor risk mitigation: Redistribution layer

- In-silicon power distribution over long distances not yet validated
  - If *stitching* yield is sub-optimal for excessive voltage drop across the chip, a **post-processing** of the sensor is needed (measurements are ongoing)

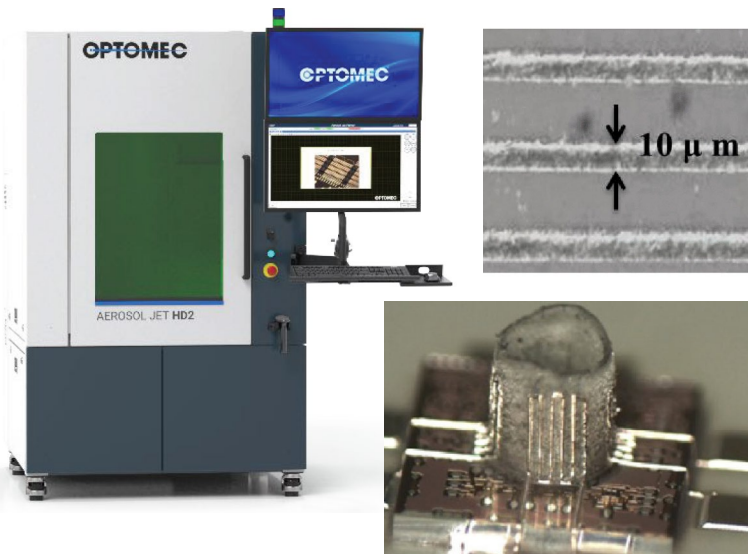


*Stitched prototype*

Fall-back options:

- MAPS-foil: embed thin MAPS into polyimide sandwich, developed within ITS3
  - Copper traces deposited on the polyimide and connected to the sensor by through-hole metallization – traditional lithography
  - Adds ~0.05%  $X_0$ , power dissipation not evaluated → not ideal for ALICE 3
- Application of a **Re-Distribution Layer (RDL)** with additive manufacturing
  - Additional copper and polyamide layer(s) added to the wafer where needed
  - Trade-off between resistance and material budget
  - **Aerosol Jet Printing (AJP)** machine available at INFN TS – UniTS:
    - 10  $\mu\text{m}$  spatial resolution, on planar and bent substrate

*AJP – conductive traces*



• **Request for 2024: inks to develop conductive traces deposition through AJP**

# ALICE 3 Vertex Layers (Iris): Vacuum technology

IRIS is constituted by 4 petals

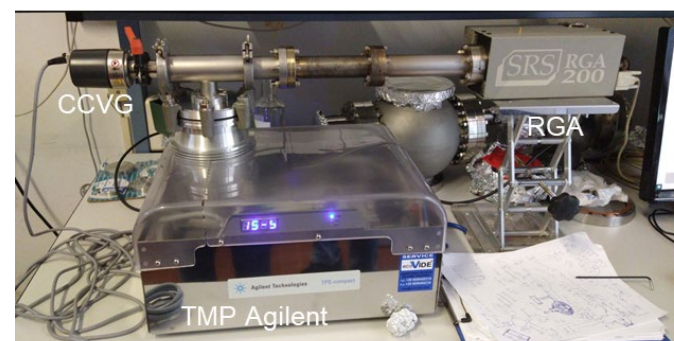
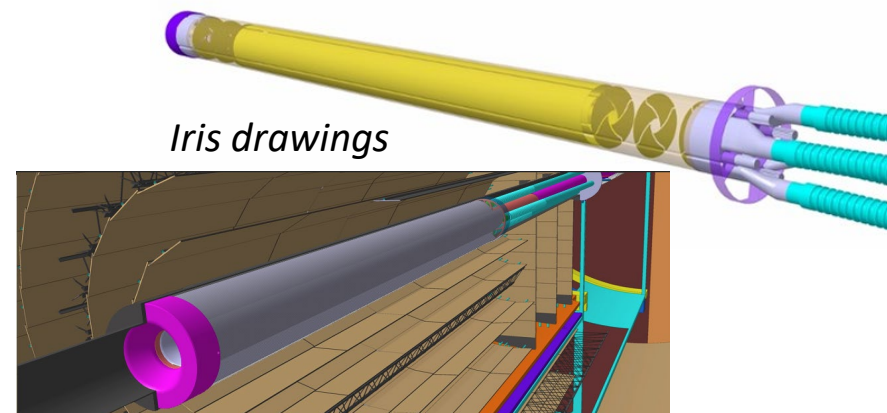
- sensors in each petal are kept in a vacuum case (secondary vacuum,  $10^{-10}$  mbar) to avoid contamination of primary vacuum

Foreseen in vacuum studies ( $\sim 10^{-10}$  mbar):

- outgassing measurements
  - vacuum level comparison
  - a.m.u. behaviour of residual gasses
  - sample weight comparison (*before and after outgassing*)
- Stress measurements on mechanical assembly
  - gluing
  - wire-bonding

Existing facility for vacuum studies (INFN BA)

**Requests for 2024: vacuum pump, vacuum chamber baking lamp, vacuum components for ALICE 3-specific upgrade**

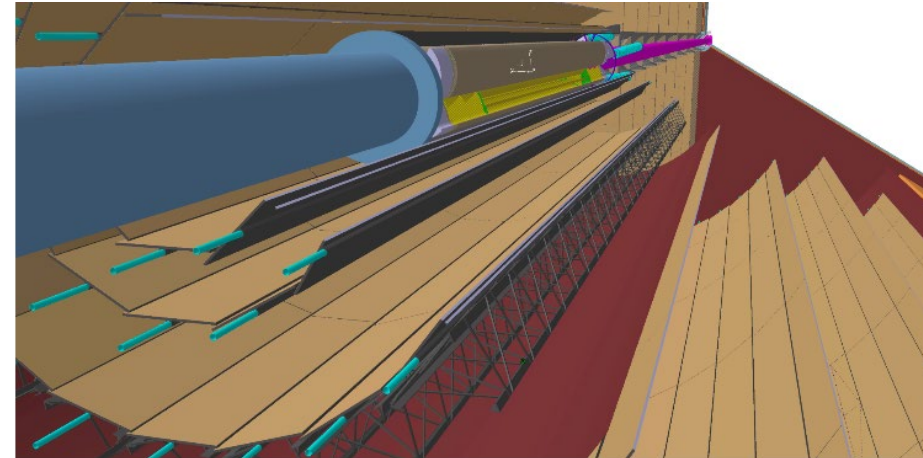


Existing equipment



# Options for Middle layers: L3-L4(-L5?)

- Lol concept
  - **Traditional stave-based layout**
    - Same sensor as larger radius layers
    - Mechanics, liquid cooling, interconnection bus
    - 1%  $X_0$  for normal incidence
    - Length = 124 cm
    - Coverage (L4):  $|\eta| < 2.9$



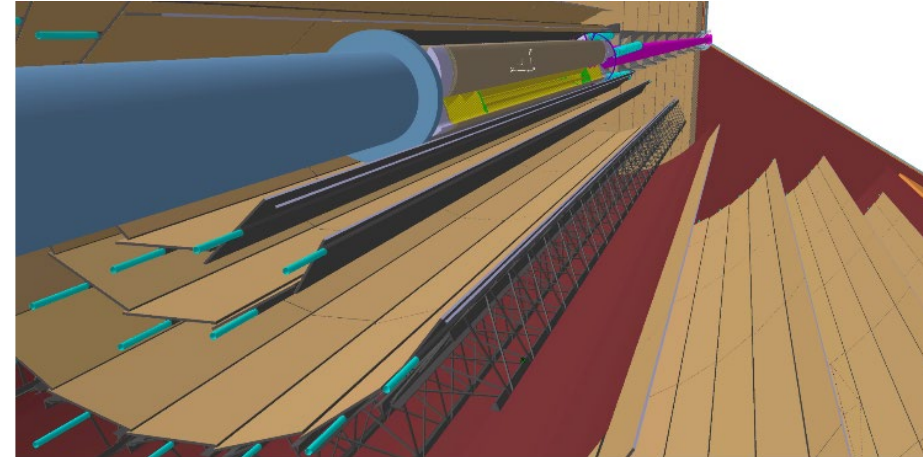
*Middle Layer layout - Lol concept*

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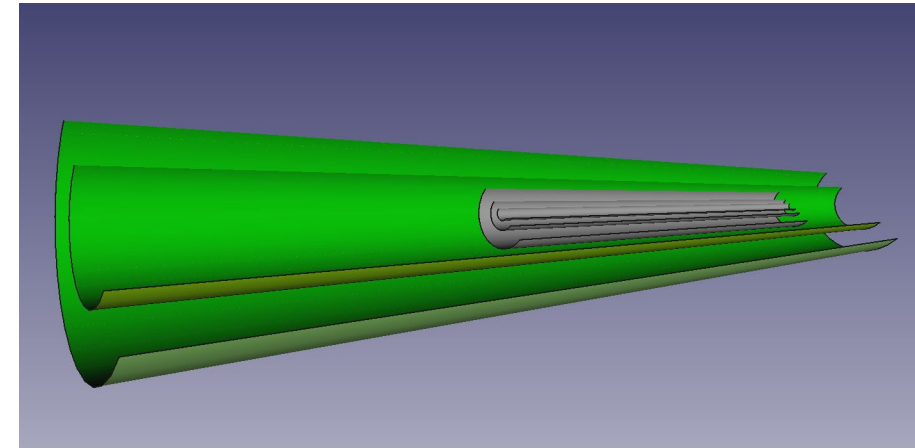


*Middle Layer layout - Lol concept*

- Possible optimised layout for L3-L4

- **Flexible sensors with minimal supports** →

- Same sensor as for the Iris layers
- Added supports and I/O structures to cover the length
- **0.1% ~ 0.3%  $X_0$**  for normal incidence
- Length = 100 cm (2x vertex layer length)
- Coverage (L4):  $|\eta| < 2.7$



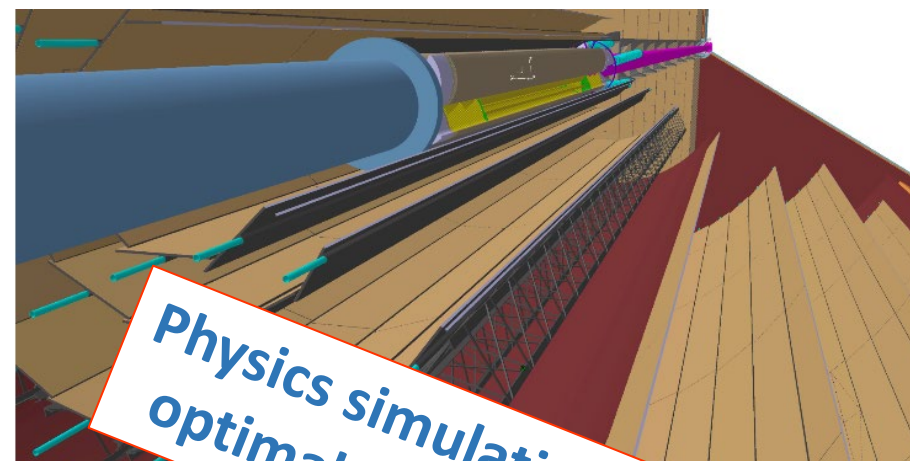
*Middle Layer layout – Optimised layout*

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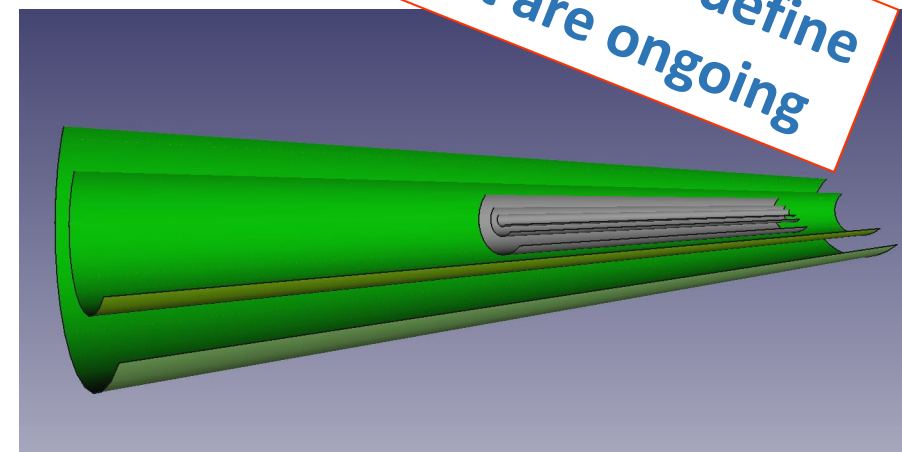


Physics simulations to define optimal layout are ongoing

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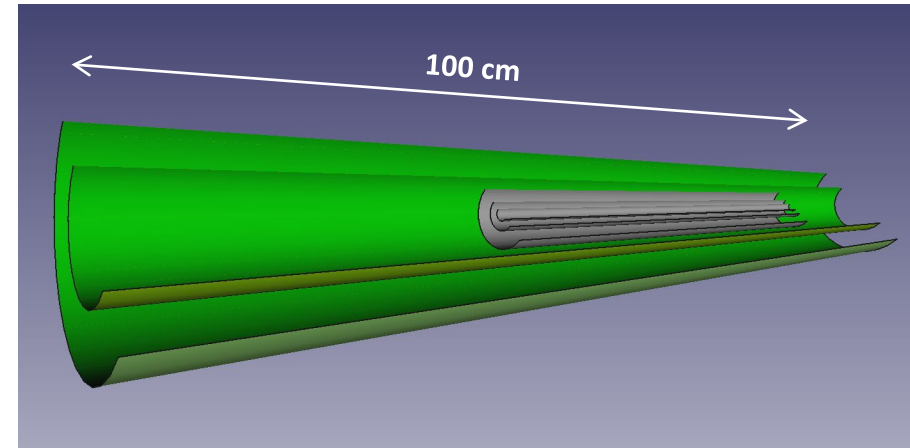


Middle Layer layout – Optimised layout

# Optimised layout for Middle layers: L3-L4(-L5?)

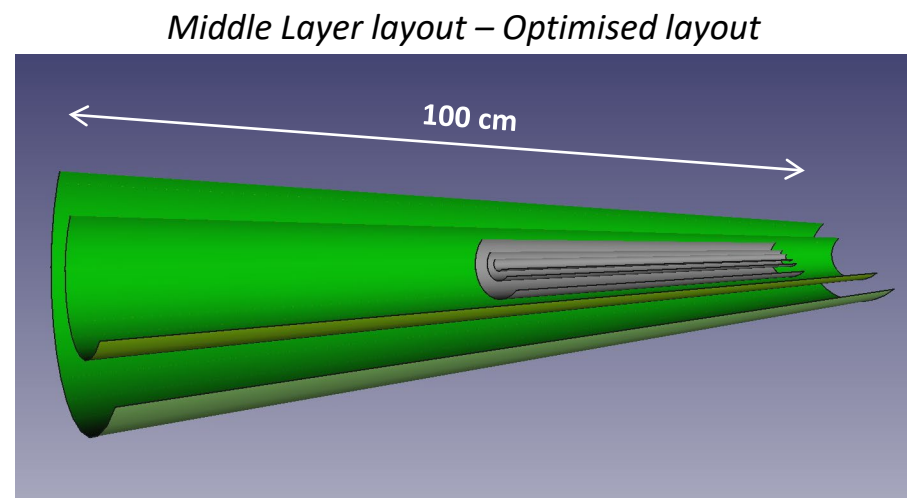
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*Middle Layer layout – Optimised layout*



# Optimised layout for Middle layers: L3-L4(-L5?)

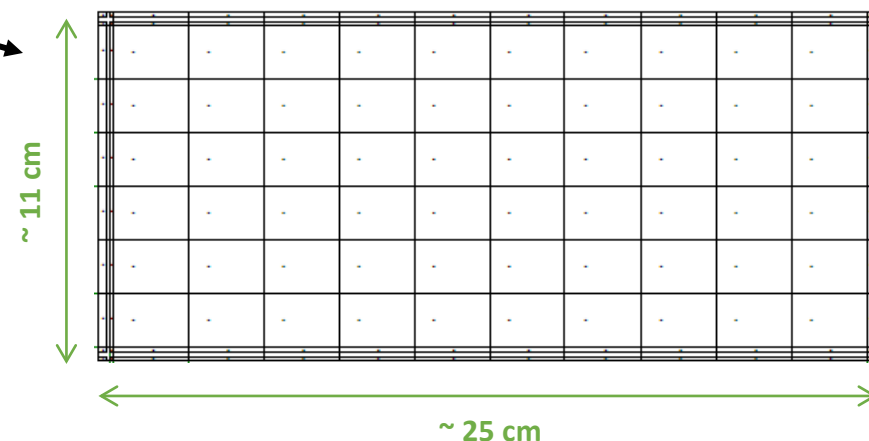
- Possible optimised layout for L3-L4
  - **Flexible sensors with minimal supports**
    - Same sensor as for the Iris layers
    - Added supports and I/O structures to cover the length
    - **0.1% ~ 0.3%  $X_0$**  for normal incidence
    - Length = 100 cm (2x vertex layer length)
    - Coverage (L4):  $|\eta| < 2.7$



\* = Allowed on 30 cm wafers

- Area =  $0.239\text{m}^2 + 0.440\text{m}^2 < \mathbf{0.7\text{m}^2}$ 
  - Layer 3 can be formed with 4x4 sensors\* ( $\sim 25 \times 6 \text{ cm}^2$ )
  - Layer 4 can be formed with 4x4 sensors\* ( $\sim 25 \times 11 \text{ cm}^2$ )

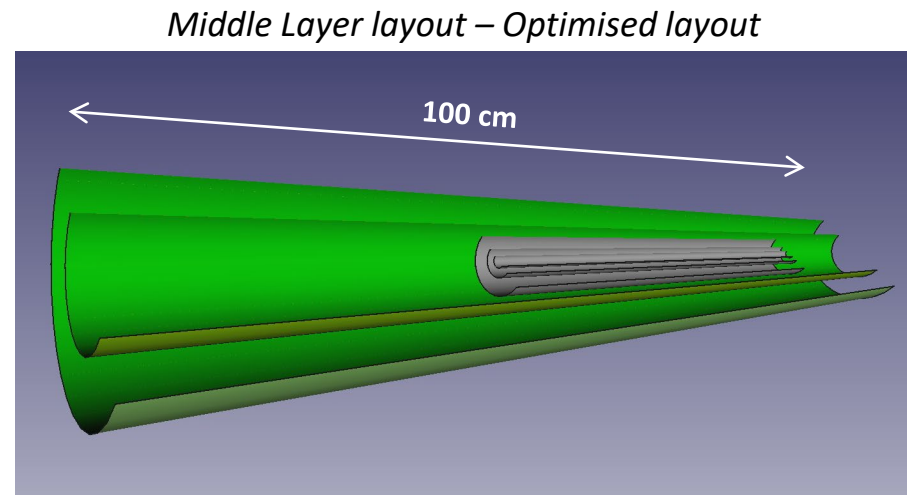
Allowed dimensions for stitched sensor on 30 cm wafer





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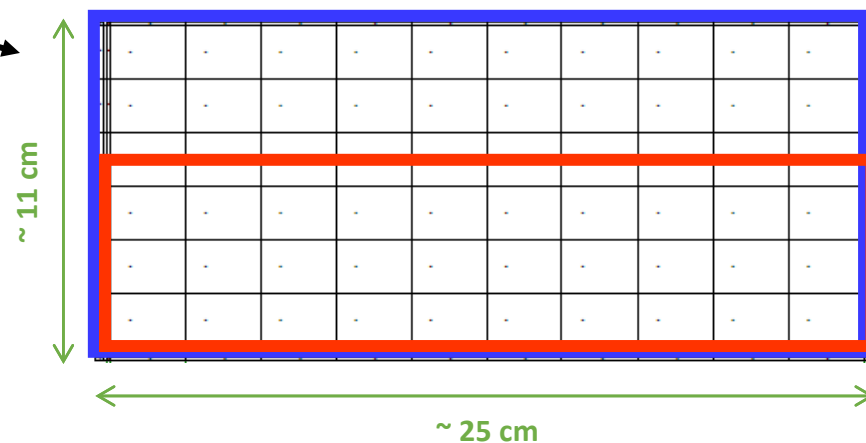
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Allowed dimensions for stitched sensor on 30 cm wafer

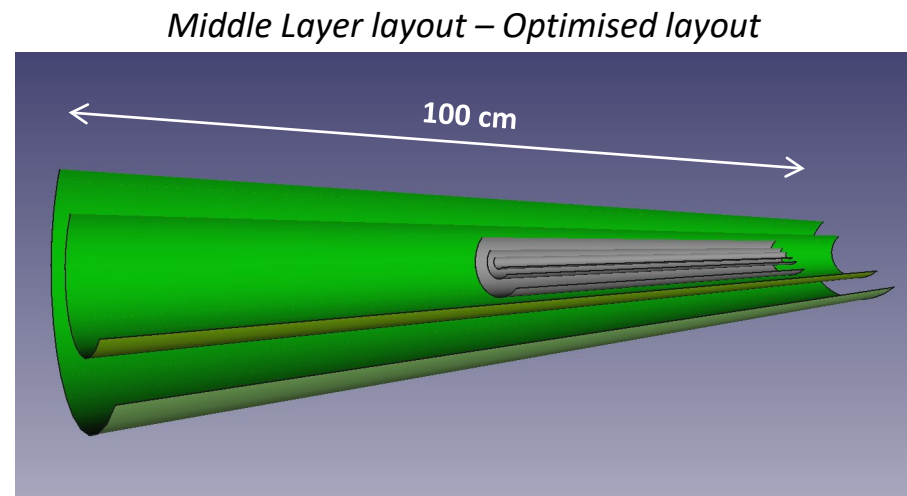


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- Material thickness of **0.1%  $X_0$**  is in reach

- Longer sensor chain with simpler mechanics/cooling wrt Vertex
- ITS3-like assembly
- Repeated to cover the length
- **Demonstrate the feasibility!**

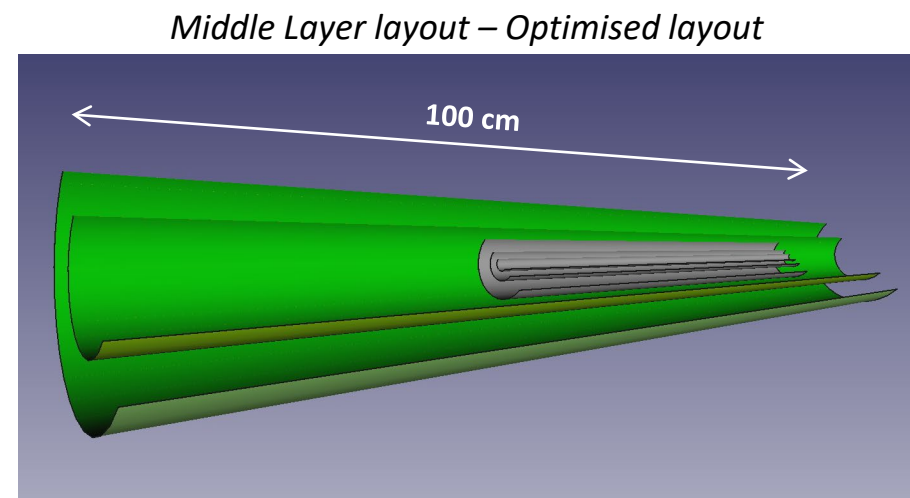


Allowed dimensions for stitched sensor on 30 cm wafer



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**Requests for 2024: carbon foam and carbon fiber to prepare rings and support structures for Middle Layer mechanical prototypes**



# INFN R&D: Inner Tracker (Vertex + Middle)

- Sensor for Vertex and Middle Layers
  - Main sensor development and characterisation
  - Adaptation for Middle Layers
- In-vacuum mechanics, cooling, interconnections
- Re-distribution layer for power & interconnections
- Middle Layers layout
  - Concepts, feasibility, prototypes

**Covered within  
ITS3 for 2024**

**BA + others**

**TS + others**

**PD, TS  
+ others**

# ALICE 3 Inner Tracker: richieste 2024



Attività'	Dettaglio	Richiesta 2024 (k€)	Sede
Sviluppo e caratterizzazione sensore	-	0	BA, BS/PV, CA, CT/ME, PD, LNF, TO, TS
Studi di vuoto	Pompa a vuoto, dispositivi di bake-out, componenti	15	BA
Prototipi meccanici Middle layers	Fibra e schiuma di carbonio sagomate	10	TS* (per TS & PD)
Strato redistribuzione con manifattura additiva	Inchiostri AJP conduttivi/isolanti	7	TS
<b>TOTALE</b>		<b>32</b>	
<b>Missioni</b>	Test in vuoto di prototipi	<b>2</b>	TS* (per tutti)



*Thank you for your attention!*

# Backup: ALICE 3 tracker – specifications

	Layer ID	Radius [cm]	Length [cm]	$<  \eta $	Area [m <sup>2</sup> ]	Tot Area [m <sup>2</sup> ] up to this Layer	Pixel pitch [um]	Tot Pixels (10 <sup>6</sup> )	Power density [mW/cm <sup>2</sup> ]	Tot Power (+20%) [W]	Max Hit Rate [10 <sup>6</sup> /cm <sup>2</sup> /s]	Required BW for Hits [Gbit/s]	Required BW for Noise [Gbit/s]	Total Installed BW [Gbit/s]
Inside the beam pipe	0	0.5	50	4.6	0.016	0.016	10	157	70	13	94	236	1.0	237
	1	1.2	50	3.7	0.038	0.053	10	377	70	32	16	97	2.4	99
	2	2.5	50	3.0	0.079	0.132	10	785	70	66	3.8	48	5.0	53
Middle Layers	3	3.8	100	3.3	0.239	0.371	10	2388	70	201	1.7	65	15.3	80
	4	7.0	100	2.7	0.440	0.811	10	4398	70	369	0.48	34	28.1	62
	5	12.0	124	2.3	0.935	1.745	50	374	20	224	0.16	24	2.4	26
	6	18.0	124	1.9	1.402	3.148	50	561	20	337	0.058	13	3.6	17
	7	30.0	124	1.4	2.337	41.972	50	935	20	561	0.026	10	6.0	16
	8	45.0	264	1.8	7.464	49.437	50	2986	20	1791	0.012	14	19.1	33
	9	60.0	264	1.5	9.953	59.389	50	3981	20	2389	6.50E-03	10	25.5	36
	10	80.0	264	1.2	13.270	72.659	50	5308	20	3185	3.70E-03	8	34.0	42

- Hit density decreases by  $O(10^4)$  from layer 0 to layer 10
- Bandwidth dominated by the vertex detector
- Noise performance critical for the outer most layers
- Bandwidth: 16 bit / hit, single pixel clusters
- Radiation load: 50 months of 24 MHz pp interactions
- Fake-hit rate:  $10^{-8}$  / pixel / event at 40 MHz readout rate

# Main R&D items for the ALICE 3 Tracker (I)

- Sensor development (ALICE 3 ER1' foreseen by 2027)
  - Challenging requirements:
    - Highest possible vertex resolution (Vertex Detector)
    - High radiation tolerance (Vertex Detector)
    - High Speed front-end circuit
    - High Data Bandwidth to handle
    - Extremely low noise (Outer Tracker)
    - Low power consumption (extremely low for Outer Tracker)
    - Single-point failure tolerance
  - At least two sensor versions need to be developed
    - Common development with fork-off?
    - Existing low-performance technology for Outer Tracker?
    - Is a third version needed for Middle Layers?
    - *In collaboration with CERN and other Institutions (ITS2/ITS3 model)*



# Main R&D items for the ALICE 3 Tracker (II)

- Iris development (L0-L1-L2, inside the beam pipe)
  - Vacuum-compatible technology
  - Retractable mechanics
  - Flexible sensors
  - *INFN groups with significant experience, strong commitment from CERN*
- Middle layers (L3-L4, outside the beam pipe)
  - Bent silicon to equip  $\sim 0.7 \text{ m}^2$  with low-material supports and I/O structures
  - Substantial data bandwidth and power consumption
  - *Well-defined item matching INFN groups' expertise*
- Sensor characterization
  - Crucial for the sensor development
  - ITS3 experience shows that a large effort is needed
  - *Easy to contribute for small/medium-sized groups*

# Resources ramping up in 2024-2028

- 8 groups involved:  
Bari, Brescia/Pavia, Cagliari, Catania/Messina, Frascati, Padova, Torino, Trieste
- **~15 FTE** (total of 25 collaborators\*) for detector R&D and construction
  - 4-5 on **sensor design**
    - 3 designers already integrated in the ITS3 design, more to come
    - Need to focus on ALICE 3-specific design quite soon
  - 6-7 on **sensor characterisation**
    - 6 groups already active participants in ITS3 test system development and sensor characterisation
  - 4 on **integration and mechanics**
    - Experience on ITS2 mechanical structure and ITS3 integration
- Adequate contribution to simulation and physics studies

\* including Researchers, Postdocs, PhD students, Engineers, Technicians

# News on available infrastructures

- Well equipped laboratories and workshops in most of the sites
  - (Automatic) probe stations, bonding facilities, CMMs, radiation sources, mechanical workshops
- Additional infrastructures
  - Vacuum laboratory, assembly clean room @ Bari
  - Assembly clean room, X-ray facility, soon cyclotron @ Padova
  - Beam test facility, assembly clean room @ Frascati
  - Assembly clean room, X-ray facility @ Torino
  - X-ray facility, future sensor and AM laboratory @ Trieste
  - ...
- **FTE and infrastructures availability expected to grow once the project starts**